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(54) Title: USING ABSOLUTE Z-HEIGHT VALUES FOR SYNERGY BETWEEN TOOLS

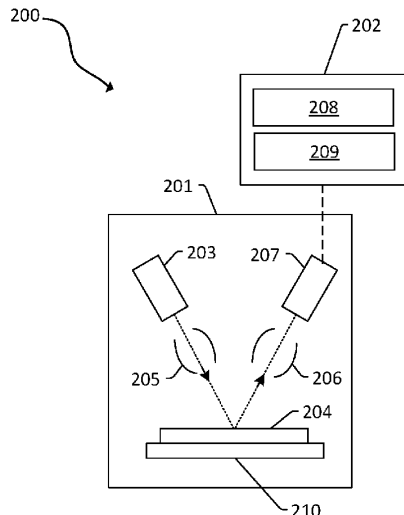


FIG. 6

(57) Abstract: A semiconductor review tool receives absolute Z-height values for the semiconductor wafer, such as a semiconductor wafer with a beveled edge. The absolute Z-height values can be determined by a semiconductor inspection tool. The semiconductor review tool reviews the semiconductor wafer within a Z-height based on the absolute Z-height values. Focus can be adjusted to within the Z-height.

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